



SEMICONDUCTOR PROCESSING WITH A REMOTE PLASMA  
SOURCE FOR SELF-CLEANING

Sato et al.

Appl. No.: Unknown. Atty Docket: ASMJP.055C1

REPLACEMENT SHEET

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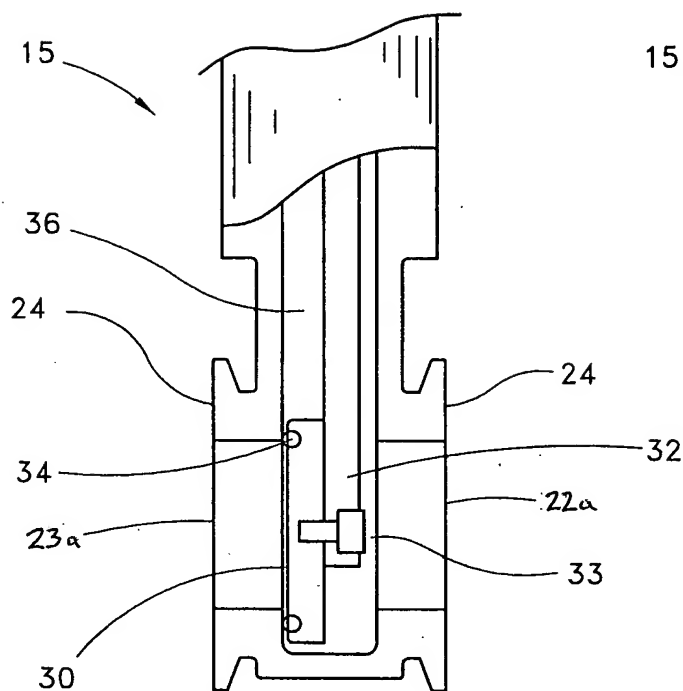


FIG. 4A

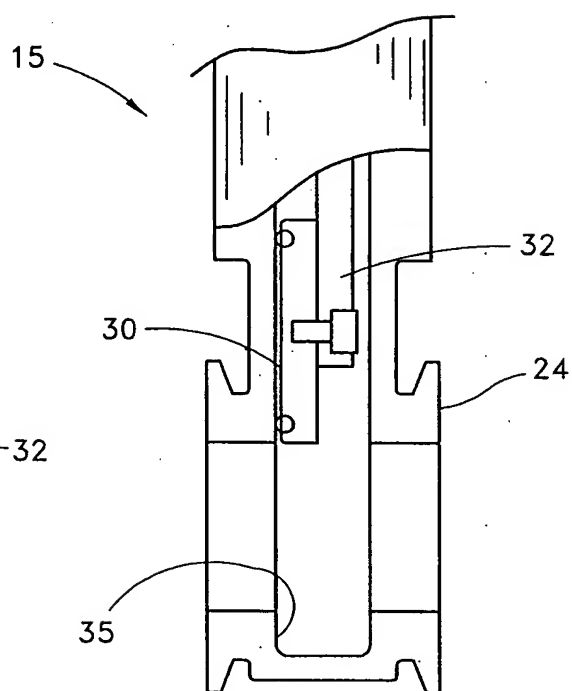


FIG. 4B